

IN THE CLAIMS

Please amend the claims as follows:

Claims 1-43 (Canceled).

Claim 44 (New): A vacuum processing apparatus, comprising:

a processing chamber, including

a lower wall;

an upper wall;

a side wall coupled to the lower wall and the upper wall; and

a plurality of pumping ports, formed in one of the lower wall, the upper wall,
or the side wall;

at least one pumping cell, integrally including a pump and a valve, coupled to a first
pumping port; and

at least one seal coupled to a second pumping port, wherein

the at least one pumping cell can be removed from the first pumping port and coupled
to a first different pumping port, and

the at least one seal can be removed from the second pumping port and coupled to a
second different pumping port such that an arrangement of the at least one pumping cell and
the at least one seal is reconfigured.

Claim 45 (New): The vacuum processing apparatus according to claim 44, wherein
the side wall having a height of at most about four inches.

Claim 46 (New): The vacuum processing apparatus according to claim 45, wherein the process chamber is made of a single unit of plate stock having a thickness of about four inches.

Claim 47 (New): The vacuum processing apparatus according to claim 46, wherein the plate stock is aluminum.

Claim 48 (New): The vacuum processing apparatus according to claim 45, wherein the plurality of pumping ports are located on the lower wall of the process chamber adjacent to a process chamber volume.

Claim 49 (New): The vacuum processing apparatus according to claim 45, wherein three pumping ports are provided on the lower wall of the process chamber symmetrically spaced about a chuck assembly provided within the process chamber.

Claim 50 (New): The vacuum processing apparatus according to claim 49, wherein three pumping cells are connected to the process chamber, each one of the three pumping cells being connected to a respective one of the three pumping ports.

Claim 51 (New): The vacuum processing apparatus according to claim 45, wherein two pumping ports are provided on the lower wall of the process chamber symmetrically spaced about a chuck assembly on opposing sides thereof.

Claim 52 (New): The vacuum processing apparatus according to claim 51, wherein two pumping cells are connected to the process chamber, each one of the two pumping cells being connected to a respective one of the two pumping ports.

Claim 53 (New): The vacuum processing apparatus according to claim 44, further comprising means for reducing open volume within the process chamber.

Claim 54 (New): The vacuum processing apparatus according to claim 53, wherein the means for reducing open volume comprises a chamber liner configured to displace open volume within the process chamber.

Claim 55 (New): The vacuum processing apparatus according to claim 44, wherein the process chamber facilitates the formation of plasma.

Claim 56 (New): A method of making an improved vacuum processing apparatus, comprising:

providing a processing chamber, including

a lower wall;

an upper wall;

a side wall coupled to the lower wall and the upper wall; and

a plurality of pumping ports, formed in one of the lower wall, the upper wall, or the side wall;

connecting at least one pumping cell, integrally including a pump and a valve, to a first pumping port; and

connecting at least one seal to a second pumping port, wherein

the at least one pumping cell can be removed from the first pumping port and coupled to a first different pumping port, and

the at least one seal can be removed from the second pumping port and coupled to a second different pumping port such that an arrangement of the at least one pumping cell and the at least one seal is reconfigured.

Claim 57 (New): The method according to claim 56, further comprising:
making the side wall with a height of at most about four inches.

Claim 58 (New): The method according to claim 57, further comprising:
making the process chamber of plate stock with a thickness of about four inches.

Claim 59 (New): The method according to claim 58, wherein the plate stock is aluminum.

Claim 60 (New): The method according to claim 57, further comprising:
making the process chamber via a molding process.

Claim 61 (New): The method according to claim 57, wherein
said lower wall is a plate and said side wall is a rolled cylinder, and
the making the process chamber includes welding the lower wall to the side wall.

Claim 62 (New): The method according to claim 57, further comprising:
providing the plurality of pumping ports on the lower wall of the process chamber adjacent to a process chamber volume.

Claim 63 (New): The method according to claim 57, further comprising:
providing a chuck assembly in the process chamber; and
providing three pumping ports on the lower wall of the process chamber
symmetrically spaced about the chuck assembly.

Claim 64 (New): The method according to claim 63, further comprising:
connecting three pumping cells to the process chamber,
wherein each one of the three pumping cells are connected to a respective one of the
three pumping ports.

Claim 65 (New): The method according to claim 57, further comprising:
providing a chuck assembly in the process chamber; and
providing two pumping ports on the lower wall of the process chamber symmetrically
spaced about the chuck assembly on opposing sides thereof.

Claim 66 (New): The method according to claim 65, further comprising:
connecting two pumping cells to the process chamber,
wherein each one of the two pumping cells are connected to a respective one of the
two pumping ports.

Claim 67 (New): The method according to claim 56, further comprising:
providing a chamber liner in the process chamber configured to displace open volume
within the process chamber.

Claim 68 (New): The method according to claim 56, further comprising:
providing an upper electrode to facilitate the formation of plasma in the process
chamber.